

Application/Control No.	Applicant(s)/Patent under Reexamination
10/698,460	SHIH, KEN
Examiner	Art Unit
Jimmy H. Nauven	2629

SEARCHED				
Class	Subclass	Date	Examiner	
345	163-166	4/28/2006	JHN	
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INTERFERENCE SEARCHED				
Class	Subclass	Date	Examiner	
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SEARCH NOTES (INCLUDING SEARCH STRATEGY)			
	DATE	EXMR	
EAST search	4/28/2006	JHN	